



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

CHIH-CHIEN LIU, et al.

Serial No. 09/546,174

Filed: April 11, 2000

For: HIGH DENSITY PLASMA CHEMICAL
VAPOR DEPOSITION PROCESS

Examiner: R. SERGENT

Art Unit: 1711

#16
10/12/02

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OCT 15 2002

TC 1700

AMENDMENT AFTER FINAL OFFICE ACTION

Assistant Commissioner of Patents
Washington, D.C. 20231

Dear Sir or Madame:

Attached please find copies of references that were discovered by our client only after the Final Office Action was entered. Please include these copies of US Patent numbers 5,854,126 and 5,219,788 in the file.

October 8, 2002

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